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IEEE JNL IEEE Journal or Magazine

IET JNL IET Journal or Magazine

IEEE CNF IEEE Conference Proceeding

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IEEE STD IEEE Standard

1. **Virtual fab technology utility simulation and its application to 300 mm CR facility design and energy reduction**

Masuda, T.; Samata, S.; Mikata, Y.;
Semiconductor Manufacturing, 2005. ISSM 2005, IEEE International Symposium on
 13-15 Sept. 2005 Page(s):17 - 20

Digital Object Identifier 10.1109/ISSM.2005.1513285

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2. **The Virtual Fab the core of future technology development**

Torres, K.; Smith, E.; McDonald, C.; Rinn Cleavelin, C.;
Advanced Semiconductor Manufacturing Conference and Workshop, 1999 IEEE/SEMI
 8-10 Sept. 1999 Page(s):222 - 226

Digital Object Identifier 10.1109/ASMC.1999.798229

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3. **A dynamic binding model for service creation in virtual fab**

Shi-Chung Chang; Tsung-Lian Chou; Ruey-Shan Guo; Yea-Huey Su; Ling-Ling Lu; I-Chang Lai;
Semiconductor Manufacturing Technology Workshop, 1998

16-17 June 1998 Page(s):131 - 138

Digital Object Identifier 10.1109/SMTW.1998.722674

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4. **Foundry technology and services**

Tsai, R.L.S.;
Semiconductor Manufacturing Technology Workshop, 1998

16-17 June 1998 Page(s):139

Digital Object Identifier 10.1109/SMTW.1998.722678

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5. **Foundry technology for the next decade**

Sun, J.Y.C.; Shang-Yi Chiang; Liu, M.;
Electron Devices Meeting, 1998. IEDM '98 Technical Digest., International
 6-9 Dec. 1998 Page(s):321 - 324

Digital Object Identifier 10.1109/IEDM.1998.746364

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